



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Zhiping Yin et al.

Title:

TRANSPARENT AMORPHOUS CARBON STRUCTURE IN SEMICONDUCTOR DEVICES

Docket No.:

303.864US1

Serial No.: 10/661,379

Filed:

September 12, 2003

Due Date: N/A

Examiner:

Christian D Wilson

Group Art Unit: 2829

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

- \underline{X} A return postcard.
- X A Supplemental Information Disclosure Statement (2 pgs.), Form 1449 (1 pg.), and copies of 7 cited documents.
- X Copy of International Search Report from Corresponding foreign Application No. PCT/US2004/029172 (15 pgs.).

Please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

Customer Number 21186

Atty: Viet V. Tong

Reg. No. 45,416

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 26 day of February, 2005.

Name

Signature

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

(GENERAL)

S/N 10/661,379

PATENT

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with 37 C.F.R. §§ 1.97 et. seq., the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified patent application. Applicants respectfully request that this Supplemental Information Disclosure Statement be entered and the documents listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to the provisions of MPEP 609, Applicants request that a copy of the 1449 form, initialed as being considered by the Examiner, be returned to the Applicants with the next official communication.

Several of the attached documents were discovered as a result of a Search Report in Applicants' corresponding foreign patent application. Enclosed for the Examiner's information is a copy of the cited documents and the Search Report.

Pursuant to 37 C.F.R. §1.97(b), it is believed that no fee or statement is required with the Supplemental Information Disclosure Statement. However, if an Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the required fees to Deposit Account No. 19-0743 in order to have this Supplemental Information Disclosure Statement considered.

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Serial No:10/661,379

Filing Date: September 12, 2003

Title: TRANSPARENT AMORPHOUS CARBON STRUCTURE IN SEMICONDUCTOR DEVICES

The Examiner is invited to contact the Applicants' Representative at the below-listed telephone number if there are any questions regarding this communication.

Pursuant to 37 C.F.R. 1.98(a)(2), Applicant believes that copies of cited U.S. Patents and Published Applications are no longer required to be provided to the Office. Notification of this change was provided in the United States Patent and Trademark Office OG Notices dated October 12, 2004. Thus, Applicant has not included copies of any US Patents or Published Applications cited with this submission. Should the Office require copies to be provided, Applicant respectfully requests that notice of such requirement be directed to Applicant's below-signed representative. Applicant acknowledges the requirement to submit copies of foreign patent documents and non-patent literature in accordance with 37 C.F.R. 1.98(a)(2).

Respectfully submitted, ZHIPING YIN ET AL.

By their Representatives, SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A. P.O. Box 2938 Minneapolis, MN 55402 (612) 373-6969

Date Fx b 25, 2005

Viet V. Tong

Reg. No. 45,416

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Signature

PTC/SB/08A(10-01)

Approved for use through 10/31/2002, OMB 651-0031

US Patent & Trademark Office: U.S. DEPARTMENT OF COMMERCE
der the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Complete if Known Substitute for form 1449A/PTO Complete if Known INFORMATION DISCLOSURE 10/661,379 **Application Number** STATEMENT BY APPLICANTP (Use as many sheets as necessary) September 12, 2003 Filing Date Yin, Zhiping **First Named Inventor** FEB 2 8 2005 2829 **Group Art Unit** Wilson, Christian **Examiner Name** Attorney Docket No: 303.864US1 Sheet 1 of 1

	US PATENT DOCUMENTS								
Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Filing Date If Appropriate					
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	US-2002/0001778A1	01/03/2002	Latchford, I, et al.	08/02/2001					
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Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	T²		
	EP-0531232A2	03/10/1993	Franke, H. G., et al.			
	EP-1154468A2	11/14/2001	Fairbairn, K., et al.			
	JP-58-204534A	11/29/1983	Obayashi, H , et al.			
	WO-03038875A2	05/08/2003	Czech, G, et al.			
	WO-2004/012246A2	02/05/2004	Bonser, D. J., et al.			

	ОТН	ER DOCUMENTS NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
		"International Search Report, for Application No. PCT/US2004/029172, date mailed December 21, 2004", 15 pages	
		LIU, W., et al., "Generating Sub-30nm Poly-Silicon Gates Using PECVD Amorphous Carbon as Hardmask and Anti-Reflective Coating", <u>Proceedings of the SPIE, 5040</u> , Optical Microlithography XVI, Yen, A, (ed.),(02/25/2003),841-848	
		SHIEH, J, et al., "Characteristics of Fluorinated Amorphous Carbon Films and Implementation of 0.15 micron Cu/a-C:F Damascene Interconnection", <u>Journal of Vacuum Science and Technology</u> , 19, (May, 2001),780-787	

DATE CONSIDERED EXAMINER